

The total summit of the mountain, it is desirable to have the relative of 1/10 R₂O<0.5. The average intensity of the total summit of the mountain is described in Japanese Industrial Standards (JIS S 0807-1994). For example, can be measured with a surface roughness meter.

[0027] Although the form in particular of the rough part of uppermost of a current collection body surface is not limited, it is desirable that it is a cone-like, for example. Moreover, as for the upper part part of a pile-shaped portion, it is desirable that it is roughish (wavy) in order to avoid concentration of the current in a charge-and-discharge reaction.

[0028] In this invention, the break of the thickness direction formed in a thin film may be formed by the charge and discharge after the first time, and may be substantially formed before charge and discharge. Before assembling a battery, after expanding the volume of a thin film, it can be made to be able to contract, and can be made to form by the method of making it work-one sec. of carrying out contraction of the lithium salt to the thin film of the an-cathode, as a method of making such a break forming in a thin film beforehand before charge and discharge. Of course, when the active material which does not contain lithium is used for a plus terminal, where contraction is carried out, you may assemble lithium. Moreover, it is good idea as a thin film separated by the break pile-shaped by forming a thin film pillar-shaped using the resist film patterned by photo lithography.

[0029] Generally silicon is divided roughly into amorphous silicon and micro crystalline silicon, polycrystalline silicon, and single crystal silicon by crystalline difference. About [520nm] one peak on the Raman spectroscopic analysis and corresponding to a crystalline region in amorphous silicon is not detected substantially. Both about [520nm] one peak on the Raman spectroscopic analysis and corresponding to a crystalline region in micro crystalline silicon and about [480nm] one peak corresponding to an amorphous field are detected substantially. Therefore, micro crystalline silicon consists of a crystalline region and an amorphous field substantially. About [480nm] one peak on the Raman spectroscopic analysis and corresponding to an amorphous field in polycrystalline silicon and single crystal silicon is not detected substantially.

[0030] In the invention, a micro crystalline silicon thin film and an amorphous silicon thin film are desirable as a silicon thin film in which the above-mentioned element is contained. Moreover, as a thin film which makes silicon a subject in the invention, a silicon germanium-alloy thin film is mentioned in addition to the above-mentioned silicon thin film. As a various germanium alloy thin film, a micro crystalline silicon germanium alloy thin film and an amorphous silicon germanium thin film are used preferably. The micro crystalline and the quality of arrangement of a silicon germanium alloy thin film can be adjusted as the above-mentioned alloy thin film. Silicon and germanium, diatomic symmetry, and since a good result is obtained in the invention, all are preferable that a result good also about the silicon.

germanium alloy which one these alloys is obtained

[J033] In this invention, although the method in particular of forming a thin film on a current collection object is not limited, a CVD method, the sputtering method, the vapor-depositing method, a thermal-spraying method, or the plating method is mentioned, for example. Also, in these thin film formation methods, a CVD method, the sputtering method, and the vapor-depositing method are used especially preferably.

[J034] The method of making the material gas which contains the above-mentioned element in the material gas of silicon in the case of a CVD method, decomposing this mixed gas, and forming a thin film, as a method of making the above-mentioned elements containing, also a thin film, for example, is mentioned. Moreover, in the case of the sputtering method, the target of silicon and the target of the above-mentioned element are arranged side by side, and the method of forming a thin film is mentioned to it, in the case of the vapor-depositing method, the source of vapor deposition of silicon and the source of vapor deposition of the above-mentioned element are arranged side by side, and the method of forming a thin film is mentioned to it.

[J035] The current collection object used in this invention will not be limited especially if a thin film can be formed by good adhesion nature on it. As an example of a current collection object, at least one can choose from copper, nickel, stainless steel, molybdenum, tungsten, and tantalum is mentioned.

[J036] As for a current collection object, it is desirable that thickness is thin, and it is preferable that it is metallic foil. Copper is mentioned as a material in which it is desirable, especially desirable that the current collection object is formed from silicon and the material which is not alloyed. As for a current collection object, it is desirable that it is copper foil, and it is desirable that the surface is copper foil by which surface roughening was carried out. Electrolytic copper foil is mentioned as such copper foil. Electrolytic copper foil is copper foil which copper is deposited on the surface of a drum, and is isolated and retained in this by winding around metal drums being inserted for example into the electrolytic solution in which copper ion was dissolved, and raising this. The surface roughening process and the surface treatment may be made by one side or both sides of electrolytic copper foil.

[J037] Moreover, you may be copper foil to which copper was deposited on the surface of rolling copper foil by the electrolyzing method, and carried out surface roughening of the surface to it. Moreover, an intermediate layer may be formed on a current collection object, and a thin film may be formed on this intermediate layer. In this case, metal contains the ingredient which is easy to diffuse in a thin film as an intermediate layer is desirable, for example, a copper layer is desirable. For example, the substrate may use the current collection object in which the copper layer was formed on the nickel foil (cathode) nickel foil film by which surface roughening was carried out. Moreover, on nickel foil by the electrolyzing method, copper ions

to dependent and the thicked film which formed on a surface roughening by this may be thin (00.55) The break formed in a thin film in this manner may be refreshed formed along the low density field formed so that it might extend in the thickness direction into a thin film. Such a low density field is formed, for example, so that it may extend toward the upper part from the rough of components of a current collection body surface.

(01.02) In this invention, it is desirable that the ingredient of a current collection object is spread in the thin film. Diffusion into the thin film of such a current collection object ingredient can raise the adhesion nature of a current collection object and a thin film. Moreover, since alloying with lithium is controlled in a diffusion lead when elements, such as lithium and copper, which is not alloyed, are spread as a current collection object ingredient, Expansion and contraction of the thin film accompanying a charge-and-discharge reaction can be controlled, and generating of stress which produces the exfoliation from the current collection object of an active material thin film can be suppressed.

(01.03) Moreover, as for the concentration of the current collection object ingredient diffused in the thin film, it is preferable to decrease as it is high and the thin film surface is approached near the current collection object, in order that control of expansion and contraction of the thin film accompanying a charge-and-discharge reaction may work more strongly toward the current collection object by having the concentration gradient of such a current collection object ingredient, it becomes easy to control that the stress which produces exfoliation of an active material thin film occurs near the current collection object. Moreover, when the concentration of a current collection object ingredient decreases, high charge-and-discharge capacity is maintainable as the thin film surface is approached.

(01.04) Moreover, as for the diffused current collection object ingredient, it is desirable to form a solid solution, without forming a thin film ingredient and an intermetallic compound into a thin film. Here, an intermetallic compound means the compound which has the specific crystal structure which metal combined by the specific ratio, while a thin film ingredient and a current collection object ingredient form not an intermetallic compound but a solid solution into a thin film, the adhesion state of a thin film and a current collection object becomes better, and higher charge and discharge capacity can be obtained.

(01.05) In addition, other than the above-mentioned elements may be added by the thin film in the invention. As such ingredients, examples, such as a phosphorus, aluminum, arsenic, selenium, boron, gallium, indium, oxygen, and nitrogen, can be mentioned, for example.

(01.06) Moreover, the thin film is the invention includes two or more layers, and may be formed in the thickness each layer composition, crystallinity, and the above-mentioned element may differ from the concentration of impurities, etc. Moreover, you may have different structure in the thickness direction of a thin film. For example, amorphous, crystallinity, the above-mentioned elements, concentration of impurities, etc., may be made same.

電極	電解質	電解質濃度	電解質種類
1	NaCl	0.1M	NaCl
2	NaCl	0.1M	NaCl
3	NaCl	0.1M	NaCl
4	NaCl	0.1M	NaCl
5	NaCl	0.1M	NaCl
6	NaCl	0.1M	NaCl
7	NaCl	0.1M	NaCl
8	NaCl	0.1M	NaCl
9	NaCl	0.1M	NaCl
10	NaCl	0.1M	NaCl
11	NaCl	0.1M	NaCl
12	NaCl	0.1M	NaCl
13	NaCl	0.1M	NaCl
14	NaCl	0.1M	NaCl
15	NaCl	0.1M	NaCl
16	NaCl	0.1M	NaCl
17	NaCl	0.1M	NaCl
18	NaCl	0.1M	NaCl
19	NaCl	0.1M	NaCl
20	NaCl	0.1M	NaCl

[0072] The battery using electrode C-N using the amorphous carbon film film which made the different species element contact according to the invention, so that clearly from Table 3 it turns out that the capacity maintenance rate is high, and the charge-discharge cycle characteristic is improving compared with the battery using the electrode X1 of the amorphous carbon film which does not contain the different species element. Moreover, since the peak of the intermediate compound of silver and a different species element is not detected into the thin film as a result of X-ray diffraction analysis, it turns out that the different species element forms alloy and a solid solution in a thin film.

[0073] Also in the above-mentioned different-species element, electrode G-I containing zinc, iron, nickel, JIRKONILUM, silver, and manganese shows the good capacity maintenance rate, and especially zinc, iron, JIRKONILUM, and nickel show the good capacity maintenance rate of 80% or more, and in the

[0074] [Experiment 3] The thin film was formed by the sputtering method where (1) pulse discharge in the electrolytic copper foil using electrolytic copper foil (15 micrometers in thickness, surface roughness Ra = 0.180 micrometer) as a current collection object. As a thin film, the silver coated thin film, the silver zinc thin film, the silver iron thin film, and the silver JIRKONILUM thin film were formed.

[0075] The conditions of sputtering were made into the conditions of the impressed electromotive force 1000V, sputtering gas (Ar) flow amount, aqueous temperature room temperature (with no heating), reaction pressure 0.022Pa (0.11 mmHg), DC pulse frequency 10kHz, and pulse width 1 milliseconds. The thin film was formed so that the thickness might be set to about 8 micrometers on the base of electrolytic copper foil (17mm x 40mm).

[0076] The silver alloy target with a size of 10cm x 20cm obtained by mixing with silver and adding each element of cobalt, zinc, iron, and JIRKONILUM at a target was used. The kind of target element = each target, concentration, and the concentration of the silver

measured in the situation that they were shown in Table 5. In addition, the highest concentration in a thin film was measured by fluorescence X-ray analysis.

[0677] Moreover, silicon was obtained from the Raman spectroscopic analysis and conducted and it checked that it was an amorphous silicon. Moreover, silicon is a subject using the electrochemical system in which the thin film was formed. The lithium secondary battery was produced like the experiment 1 and the experiment 2. And the charge-discharge cycle characteristic was evaluated like the experiment 1 and the experiment 2. A result is shown in Table 5, in addition, the comparison electrode X2 often formed the amorphous silicon thin film as comparison using crystalline silicon as a target was produced. The result of the lithium secondary battery using the comparison electrode X2 is also under study shown in Table 5.

[0678]

[Table 5]

No.	Specimen	XPS			XRD	Raman	SEM	Cyclic voltammetry
		Si 2p	Si 2s	Si 2p				
1	Si	7.5	3.5	1.5	1.5	1.5	1.5	1.5
2	Si	2.5	1.5	1.5	1.5	1.5	1.5	1.5
3	Si	2.5	1.5	1.5	1.5	1.5	1.5	1.5
4	Si	1.5	1.5	1.5	1.5	1.5	1.5	1.5
5	Si	1.5	1.5	1.5	1.5	1.5	1.5	1.5
6	Si	1.5	1.5	1.5	1.5	1.5	1.5	1.5
7	Si	1.5	1.5	1.5	1.5	1.5	1.5	1.5

[0679] The battery using electrode X2 using the amorphous silicon thin film which made the different species element random according to the invention 1 so that mostly from Table 6 it turns out that the capacity maintenance rate is high and the charge-discharge cycle characteristic is improving compared with the battery using the electrode X2 of the amorphous silicon thin film which does not contain the different-species element formed on the same conditions. Moreover, into the thin film, the peak of the insoluble compound of silicon and a different species element was not accepted as a result of X-ray diffraction analysis. Therefore it turns out that the different-species element forms silicon and a solid solution in a thin film.

[0680] About Electrode C, it is at the end time of 4 cycles. It took out, and SEM observation was performed. The break which was the trough of underlayers on the surface of a thin film is an end over the words that film was formed in the thickness direction, and the result checked that the thin film was separated by this break-pole shaped.

[0681] Moreover, Si weight per unit area made a lead quantity by fluorescence X-ray analysis was checked by film thickness, and it asked for the weight density of Si per unit silicon, in the electrode X2, in spite of having measured about 10 weight % of Si atom % with Electrode C.

